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UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 6,819,117 B2
DATED : November 16, 2004
INVENTOR(S) : Kenneth R. Wilsher

Page 1 of 2

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Title page,

Item [56], **References Cited**, U.S. PATENT DOCUMENTS, insert the following:

-- 5,940,545 08/1999 Kash et al. --
-- 6,028,952 02/2000 Kash et al. --
-- 6,172,512 01/2001 Evans et al. --
-- 6,304,668 10/2001 Evans et al. --

OTHER PUBLICATIONS, insert the following:

-- J. Bude, *Hot-carrier luminescence in Si*, PHYS. REV. B, 45(11), 15 March 1992, pages 5848-5856 --

-- S. Villa et al., *Photon emission from hot electrons in silicon*, PHYS. REV. B, 52 (15), 15 October 1995-I, pages 10993-10999 --

-- J. Kash et al., *Full Chip Optical Imaging of Logic State Evolution in CMOS Circuits*, IEDM 96 Late News Paper (1996) 1, pages 934-936 --

-- D. Knebel et al., *Diagnosis and Characterization of Timing-Related Defects by Time-Dependent Light Emission*, ITC PROCEEDINGS 1998 --

-- M. Bruce et al., *Waveform Acquisition from the Backside of Silicon Using Electra-Optic Probing*, PROCEEDINGS FROM THE 25th INTERNATIONAL SYMPOSIUM FOR TESTING AND FAILURE ANALYSIS, 14-18 November 1999, pages 19-25 --

-- T. Eiles et al., *Optical Probing of VLSI IC's from the Silicon Backside*, PROCEEDINGS FROM THE 25TH INTERNATIONAL SYMPOSIUM FOR TESTING AND FAILURE ANALYSIS, 14-18 November 1999, pages 27-33--

-- M. McManus, *Picosecond Imaging Circuit Analysis of the IBM G6 Microprocessor Cache*, PROCEEDINGS FROM THE 25TH INTERNATIONAL SYMPOSIUM FOR TESTING AND FAILURE ANALYSIS, 14-18 November 1999, pages 35-38 --

-- N. Goldblatt et al., *Unique and Practical IC Timing Analysis Tool Utilizing Intrinsic Photon Emission*, MICROELECTRONICS RELIABILITY 41 (2001) 1507-1512 --

-- G. Dajee et al., *Practical, Non-Invasive Optical Probing for Flip-Chip Devices*, ITC Paper 15.3 (Baltimore, October 28 – November 2, 2001) 433-442 --

-- IDS® PICA, *Advanced Optical Imaging for Analysis of 0.13-micron and SOI Devices*, Schlumberger Semiconductor Solutions brochure printed 3/01, four pages --

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Page 2 of 2

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Title page, (cont.)

-- FOREIGN PATENT DOCUMENTS 0 937 989 A2 08/1999 EPO --

Signed and Sealed this

Nineteenth Day of April, 2005

A handwritten signature in black ink, appearing to read "Jon W. Dudas". The signature is stylized with a large, looped initial "J" and a distinct "D" at the end.

JON W. DUDAS
Director of the United States Patent and Trademark Office